

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/671,922
Confirmation No.8459
Filing Date September 24, 2003
Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Gurley, Lynne Ann
Attorney's Docket No.MI22-2296
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over
Semiconductor Substrates

RESPONSE TO AUGUST 1, 2006 FINAL OFFICE ACTION
TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENTS

Introductory Comments

In reply to the Final Office Action of August 1, 2006, applicant amends and remarks
as follows.